## => d his

## (FILE 'HOME' ENTERED AT 20:39:16 ON 17 SEP 2004)

	FILE '	REGISTRY' ENTERED AT 20:39:30 ON 17 SEP 2004
Ll		SCREEN 970 AND 2067
L2		STRUCTURE UPLOADED
L3		QUE L2 AND L1
L4		50 S L3 SSS SAM
L5		SCREEN 970 AND 2067
L6		STRUCTURE UPLOADED
L7		QUE L6 AND L5
L8		39 S L7 SSS SAM
L9		SCREEN 970 AND 2067
L10		STRUCTURE UPLOADED
L11		QUE L10 AND L9
L12		19 S L11 SSS SAM
L13		102 S L4 OR L8 OR L12
	FILE '	HCAPLUS, CAPLUS, USPATFULL' ENTERED AT 20:41:37 ON 17 SEP 2004
L14		238 S L13
L15		130 DUPLICATE REMOVE L14 (108 DUPLICATES REMOVED)
L16		301 S OXIME SULFONATE
L17		3 S L16 AND L14
L18		9 S L14 AND (RESIST OR PHOTORESIST)
L19		6 S L18 NOT L17

=> screen 970 AND 2067

L5 SCREEN CREATED

=>

Uploading C:\Program Files\Stnexp\Queries\10642576-2.str

L6 STRUCTURE UPLOADED

=> que L6 AND L5

QUE L6 AND L5 L7

=> d

L7 HAS NO ANSWERS

L5

SCR 970 AND 2067

STR

G1
$$CF_2$$
 $CF_2$ 
 $CF_2$ 

Structure attributes must be viewed using STN Express query preparation. L7 QUE ABB=ON PLU=ON L6 AND L5

=> s 17 sss sam

SAMPLE SEARCH INITIATED 20:40:33 FILE 'REGISTRY' SAMPLE SCREEN SEARCH COMPLETED - 415 TO ITERATE

100.0% PROCESSED

415 ITERATIONS

SEARCH TIME: 00.00.01

39 ANSWERS

FULL FILE PROJECTIONS:

ONLINE \*\*COMPLETE\*\*

\*\*COMPLETE\*\* BATCH

PROJECTED ITERATIONS:

7078 TO

406 TO

PROJECTED ANSWERS:

1154

9522

=> ....Testing the current file.... screen

ENTER SCREEN EXPRESSION OR (END):end

=> screen 970 AND 2067

L9 SCREEN CREATED

=>

Uploading C:\Program Files\Stnexp\Queries\10642576-1.str

L10 STRUCTURE UPLOADED

=> que L10 AND L9

L11 QUE L10 AND L9

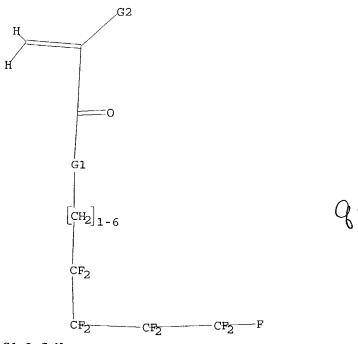
=> d

L11 HAS NO ANSWERS

L9

SCR 970 AND 2067

L10 STR



G1 O, S, N

G2 CH2, H

Structure attributes must be viewed using STN Express query preparation. L11 QUE ABB=ON PLU=ON L10 AND L9

=> d

L11 HAS NO ANSWERS

L9

SCR 970 AND 2067

L10

STR

$$G_2$$
 $G_1$ 
 $C_{F_2}$ 
 $C_{F_2}$ 
 $C_{F_2}$ 
 $C_{F_2}$ 
 $C_{F_2}$ 
 $C_{F_2}$ 
 $C_{F_2}$ 
 $C_{F_2}$ 
 $C_{F_2}$ 
 $C_{F_2}$ 

9=2

G1 O,S,N G2 CH2,H

Structure attributes must be viewed using STN Express query preparation. L11 QUE ABB=ON PLU=ON L10 AND L9

=> s l11 sss sam SAMPLE SEARCH INITIATED 20:41:17 FILE 'REGISTRY' SAMPLE SCREEN SEARCH COMPLETED - 458 TO ITERATE

100.0% PROCESSED 458 ITERATIONS SEARCH TIME: 00.00.01

19 ANSWERS

FULL FILE PROJECTIONS: ON

ONLINE \*\*COMPLETE\*\*

BATCH \*\*COMPLETE\*\*

PROJECTED ITERATIONS:

7877 TO 10443

PROJECTED ANSWERS:

119 TO 641

L12

19 SEA SSS SAM L10 AND L9

=> d his

(FILE 'HOME' ENTERED AT 20:39:16 ON 17 SEP 2004)

FILE 'REGISTRY' ENTERED AT 20:39:30 ON 17 SEP 2004 L1 SCREEN 970 AND 2067 L2STRUCTURE UPLOADED L3 QUE L2 AND L1 L450 S L3 SSS SAM L5 SCREEN 970 AND 2067 STRUCTURE UPLOADED L6 L7QUE L6 AND L5 L839 S L7 SSS SAM L9 SCREEN 970 AND 2067 L10 STRUCTURE UPLOADED

=> screen 970 AND 2067

## L1 SCREEN CREATED

=>

Uploading C:\Program Files\Stnexp\Queries\10642576-3.str

L2 STRUCTURE UPLOADED

=> que L2 AND L1

L3 QUE L2 AND L1

=> d

L3 HAS NO ANSWERS

L1 SCR 970 AND 2067

L2 STR

G1 
$$CF_2$$
  $CF_2$   $CF_2$ 

G1 0, S, N G2 CH2, H

Structure attributes must be viewed using STN Express query preparation. L3  $$\tt QUE $\tt ABB=ON $\tt PLU=ON $\tt L2 $\tt AND $\tt L1 $\tt$ 

50 ANSWERS

=> s 13

SAMPLE SEARCH INITIATED 20:48:59 FILE 'REGISTRY'
SAMPLE SCREEN SEARCH COMPLETED - 350 TO ITERATE

100.0% PROCESSED 350 ITERATIONS INCOMPLETE SEARCH (SYSTEM LIMIT EXCEEDED)

SEARCH TIME: 00.00.01

FULL FILE PROJECTIONS: ONLINE \*\*COMPLETE\*\*
BATCH \*\*COMPLETE\*\*

PROJECTED ITERATIONS: 5878 TO 8122

PROJECTED ANSWERS: 2990 TO 4648

L4 50 SEA SSS SAM L2 AND L1

L11 QUE L10 AND L9 L12 19 S L11 SSS SAM

=> s 14 or 18 or 112

L13 102 L4 OR L8 OR L12

=> FIL HCAPLUS, CAPLUS, USPATFULL COST IN U.S. DOLLARS

SINCE FILE TOTAL ENTRY SESSION

FULL ESTIMATED COST

1.68 1.89

FILE 'HCAPLUS' ENTERED AT 20:41:37 ON 17 SEP 2004
USE IS SUBJECT TO THE TERMS OF YOUR STN CUSTOMER AGREEMENT.
PLEASE SEE "HELP USAGETERMS" FOR DETAILS.

COPYRIGHT (C) 2004 AMERICAN CHEMICAL SOCIETY (ACS)

FILE 'CAPLUS' ENTERED AT 20:41:37 ON 17 SEP 2004
USE IS SUBJECT TO THE TERMS OF YOUR STN CUSTOMER AGREEMENT.
PLEASE SEE "HELP USAGETERMS" FOR DETAILS.
COPYRIGHT (C) 2004 AMERICAN CHEMICAL SOCIETY (ACS)

FILE 'USPATFULL' ENTERED AT 20:41:37 ON 17 SEP 2004
CA INDEXING COPYRIGHT (C) 2004 AMERICAN CHEMICAL SOCIETY (ACS)

=> s 113 L14 238 L13

=> duplicates remove 114

DUPLICATE PREFERENCE IS 'HCAPLUS, CAPLUS, USPATFULL'

KEEP DUPLICATES FROM MORE THAN ONE FILE? Y/(N):n

PROCESSING COMPLETED FOR L14

L15 130 DUPLICATE REMOVE L14 (108 DUPLICATES REMOVED)

=> s 116 and 114

L17 3 L16 AND L14

=> d 117 1-3 ibib hitstr

L17 ANSWER 1 OF 3 HCAPLUS COPYRIGHT 2004 ACS on STN

ACCESSION NUMBER:

2004:200910 HCAPLUS

DOCUMENT NUMBER:

140:243596

TITLE:

Chemically amplified positive photoresists suppressing

development defects

INVENTOR(S):

Momota, Atsushi

PATENT ASSIGNEE(S):

Fuji Photo Film Co., Ltd., Japan

SOURCE:

Jpn. Kokai Tokkyo Koho, 69 pp.

CODEN: JKXXAF

DOCUMENT TYPE:

Patent Japanese

LANGUAGE:

Japan

FAMILY ACC. NUM. COUNT: 1

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
JP 2004078105	A2	20040311	JP 2002-241946	20020822
US 2004048190	A1	20040311	US 2003-642576	20030819
PRIORITY APPLN. INFO.:			JP 2002-241946 A	20020822
OTHER SOURCE(S):	MARPAT	140:243596		

IT 668476-75-3P

RL: IMF (Industrial manufacture); MOA (Modifier or additive use); TEM

CM 1

CRN 114349-68-7 CMF C16 H38 O2 Si4

CM 2

CRN 27905-45-9 CMF C13 H7 F17 O2

$$_{\rm F_3C-\ (CF_2)}^{\rm O}_{\, 7-\ CH_2-\ CH_2-\ O-\ C-\ CH}^{\rm CH_2-\ CH_2}$$

CM 3

CRN 26915-72-0 CMF (C2 H4 O)n C5 H8 O2 CCI PMS

$$\begin{array}{c|c} H_2C & O \\ \parallel & \parallel & \\ \text{Me-} & C-C \end{array} \qquad \begin{array}{c} O-CH_2-CH_2 \end{array} \qquad \begin{array}{c} O \\ D \end{array} \qquad \begin{array}{c} O \\ D \end{array}$$

CM 4

CRN 80-62-6 CMF C5 H8 O2

$$\begin{array}{c|c} ^{H_2C} & \text{O} \\ \parallel & \parallel \\ \text{Me-} & \text{C-} & \text{C-} & \text{OMe} \end{array}$$

CM 5

CRN 79-10-7 CMF C3 H4 O2

L17 ANSWER 2 OF 3 CAPLUS COPYRIGHT 2004 ACS on STN

ACCESSION NUMBER:

2004:200910 CAPLUS

DOCUMENT NUMBER:

140:243596

TITLE:

Chemically amplified positive photoresists suppressing

present

development defects

INVENTOR(S):

Momota, Atsushi

PATENT ASSIGNEE(S): SOURCE:

Fuji Photo Film Co., Ltd., Japan Jpn. Kokai Tokkyo Koho, 69 pp.

CODEN: JKXXAF

DOCUMENT TYPE:

Patent Japanese

LANGUAGE:

FAMILY ACC. NUM. COUNT: PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
JP 2004078105	A2	20040311	JP 2002-241946	20020822
US 2004048190	A1	20040311	US 2003-642576	20030819
RITY APPLN. INFO.:			JP 2002-241946 A	20020822

PRIORITY APPLN. INFO

MARPAT 140:243596

IT 668476-75-3P

RL: IMF (Industrial manufacture); MOA (Modifier or additive use); TEM (Technical or engineered material use); PREP (Preparation); USES (Uses) (surfactants; chemical amplified pos. photoresists containing fluoroalkyl acrylate-polymerized surfactants and suppressing development defects)

RN CN

668476-75-3 CAPLUS

2-Propenoic acid, 2-methyl-, methyl ester, polymer with 3,3,4,4,5,5,6,6,7,7,8,8,9,9,10,10,10-heptadecafluorodecyl 2-propenoate,  $\alpha$ -(2-methyl-1-oxo-2-propenyl)- $\omega$ -methoxypoly(oxy-1,2-ethanediyl), 2-propenoic acid and 3-[2,2,2-trimethyl-1,1-bis(trimethylsilyl)disilanyl]propyl 2-methyl-2-propenoate (9CI) (CA INDEX NAME)

CM 1

CRN 114349-68-7 CMF C16 H38 O2 Si4

CM 2

CRN 27905-45-9 CMF C13 H7 F17 O2

$$\begin{array}{c} \text{O} \\ \parallel \\ \text{F}_{3}\text{C---} (\text{CF}_{2})_{7} - \text{CH}_{2} - \text{CH}_{2} - \text{O---} \text{C---} \text{CH} \underline{\hspace{1cm}} \text{CH}_{2} \end{array}$$

CM 3

CRN 26915-72-0

CMF (C2 H4 O)n C5 H8 O2

CCI PMS

CM 4

CRN 80-62-6 CMF C5 H8 O2

CM 5

CRN 79-10-7 CMF C3 H4 O2

L17 ANSWER 3 OF 3 USPATFULL on STN

ACCESSION NUMBER:

2004:63672 USPATFULL

TITLE:

Positive photoresist composition

INVENTOR(S):

Momota, Makoto, Shizuoka, JAPAN

PATENT ASSIGNEE(S):

FUJI PHOTO FILM CO., LTD. (non-U.S. corporation)

---

TAT NO

presention

	NUMBER	KIND	DATE	
PATENT INFORMATION:	US 2004048190	A1	20040311	
APPLICATION INFO.:	US 2003-642576	A1	20030819	(10)

ATT TAKES CITS

NUMBER DATE
PRIORITY INFORMATION: JP 2002-241946 20020822

DOCUMENT TYPE:

Utility APPLICATION

FILE SEGMENT: LEGAL REPRESENTATIVE:

SUGHRUE MION, PLLC, 2100 PENNSYLVANIA AVENUE, N.W.,

WASHINGTON, DC, 20037

NUMBER OF CLAIMS:

EXEMPLARY CLAIM:

1 1349

LINE COUNT:

CAS INDEXING IS AVAILABLE FOR THIS PATENT.

IT 668476-75-3P

(surfactants; chemical amplified pos. photoresists containing fluoroalkyl acrylate-polymerized surfactants and suppressing development defects)

RN 668476-75-3 USPATFULL CN 2-Propenoic acid, 2-me

2-Propenoic acid, 2-methyl-, methyl ester, polymer with 3,3,4,4,5,5,6,6,7,7,8,8,9,9,10,10,10-heptadecafluorodecyl 2-propenoate, α-(2-methyl-1-oxo-2-propenyl)-ω-methoxypoly(oxy-1,2-ethanediyl), 2-propenoic acid and 3-[2,2,2-trimethyl-1,1-bis(trimethylsilyl)disilanyl]propyl 2-methyl-2-propenoate (9CI) (CA INDEX NAME)

CM 1

CRN 114349-68-7 CMF C16 H38 O2 Si4

CM 2

CRN 27905-45-9 CMF C13 H7 F17 O2

$$\begin{array}{c} \text{O} \\ \parallel \\ \text{F}_{3}\text{C---} (\text{CF}_{2})_{7} - \text{CH}_{2} - \text{CH}_{2} - \text{O---} \text{C---} \text{CH} = \text{CH}_{2} \\ \end{array}$$

CM 3

CRN 26915-72-0

CMF (C2 H4 O)n C5 H8 O2

CCI PMS

$$H_2C$$
 O  $\parallel$   $\parallel$   $\parallel$  O  $CH_2-CH_2$  OMe

CM 4

CRN 80-62-6 CMF C5 H8 O2

CM 5

CRN 79-10-7 CMF C3 H4 O2

L19 ANSWER 1 OF 6 HCAPLUS COPYRIGHT 2004 ACS on STN

ACCESSION NUMBER:

2003:735196 HCAPLUS

DOCUMENT NUMBER:

139:267983

TITLE:

Positive-working photoresist composition

containing polymer with fluoro-aliphatic group

INVENTOR(S):

Fujimori, Toru

PATENT ASSIGNEE(S):

Fuji Photo Film Co., Ltd., Japan

SOURCE:

Jpn. Kokai Tokkyo Koho, 88 pp.

CODEN: JKXXAF

DOCUMENT TYPE:

Patent

LANGUAGE:

Japanese

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
JP 2003262952	A2	20030919	JP 2002-65444	20020311
PRIORITY APPLN. INFO.:			JP 2002-65444	20020311

ΙT 602299-35-4

> RL: MOA (Modifier or additive use); TEM (Technical or engineered material use); USES (Uses)

(surfactant; pos. photoresist composition containing polymer with fluoro-aliphatic group)

RN602299-35-4 HCAPLUS

CN 2-Propenoic acid, 2-methyl-, 3,3,4,4,5,5,6,6,7,7,8,8,9,9,10,10,10heptadecafluorodecyl ester, polymer with  $\alpha$ -(1-oxo-2-propenyl)- $\omega$ -hydroxypoly(oxy-1,2-ethanediyl) and  $\alpha$ -(1-oxo-2-propenyl)ω-methoxypoly[oxy(methyl-1,2-ethanediyl)] (9CI) (CA INDEX NAME)

CM 1

CRN 83844-54-6

CMF (C3 H6 O)n C4 H6 O2

CCI IDS, PMS

$$H_2C = CH - C - C - C_3H_6) - n OMe$$

CM 2

CRN 26403-58-7

(C2 H4 O)n C3 H4 O2 CMF

CCI PMS

$$H_2C$$
 —  $CH_2$  —

CM3

CRN 1996-88-9 CMF C14 H9 F17 O2

$$\begin{array}{c|c} & \text{O} & \text{CH}_2 \\ \parallel & \parallel \\ \text{F}_3\text{C--} (\text{CF}_2) & \text{7--} \text{CH}_2 - \text{CH}_2 - \text{O--} \text{C--} \text{C--} \text{Me} \end{array}$$

L19 ANSWER 2 OF 6 HCAPLUS COPYRIGHT 2004 ACS on STN

ACCESSION NUMBER:

1998:335551 HCAPLUS

DOCUMENT NUMBER:

129:54119

TITLE:

N-Polyfluoroalkyl-substituted (meth)acrylamides, their

(polymer) films, and photoresists using the

same

INVENTOR(S):

Miyashita, Tokuji

CODEN: JKXXAF

PATENT ASSIGNEE(S):

Chisso Corp., Japan; Miyashita, Tokuji

SOURCE:

Jpn. Kokai Tokkyo Koho, 11 pp.

DOCUMENT TYPE:

Patent

LANGUAGE:

Japanese

FAMILY ACC. NUM. COUNT:

1

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
	<del>-</del>			
JP 10139747 PRIORITY APPLN. INFO.:	A2	19980526	JP 1996-312953	19961108
OTHER SOURCE(S):	МАКРАТ	129:54119	JP 1996-312953	19961108

IT 208589-71-3P

RL: PRP (Properties); SPN (Synthetic preparation); TEM (Technical or engineered material use); PREP (Preparation); USES (Uses)

(LB films of N-polyfluoroalkyl(meth)acrylamides and their polymers with good water repellency, photosensitivity, and slip property)

RN 208589-71-3 HCAPLUS

CN 2-Propenamide, N-(3,3,4,4,5,5,6,6,7,7,8,8,9,9,10,10,10-heptadecafluorodecyl)-, homopolymer (9CI) (CA INDEX NAME)

CM 1

CRN 208589-64-4 CMF C13 H8 F17 N O

$$\begin{array}{c} \text{O} \\ || \\ \text{F}_3\text{C---} (\text{CF}_2)_7 - \text{CH}_2 - \text{CH}_2 - \text{NH} - \text{C---} \text{CH} = \text{CH}_2 \end{array}$$

L19 ANSWER 3 OF 6 CAPLUS COPYRIGHT 2004 ACS on STN

ACCESSION NUMBER:

2003:735196 CAPLUS

DOCUMENT NUMBER:

139:267983

TITLE:

SOURCE:

Positive-working photoresist composition

containing polymer with fluoro-aliphatic group

INVENTOR(S): Fujimori, Toru

PATENT ASSIGNEE(S):

Fuji Photo Film Co., Ltd., Japan Jpn. Kokai Tokkyo Koho, 88 pp.

CODEN: JKXXAF

DOCUMENT TYPE:

Patent

LANGUAGE:

Japanese

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

PATENT NO.

KIND DATE

APPLICATION NO.

DATE

JP 2003262952 A2 20030919 JP 2002-65444

JP 2002-65444

20020311

PRIORITY APPLN. INFO.:

JP 2002-65444

20020311

IT 602299-35-4

 ${\tt RL}\colon {\tt MOA}$  (Modifier or additive use);  ${\tt TEM}$  (Technical or engineered material use);  ${\tt USES}$  (Uses)

(surfactant; pos. **photoresist** composition containing polymer with fluoro-aliphatic group)

RN 602299-35-4 CAPLUS

CN 2-Propenoic acid, 2-methyl-, 3,3,4,4,5,5,6,6,7,7,8,8,9,9,10,10,10-heptadecafluorodecyl ester, polymer with  $\alpha$ -(1-oxo-2-propenyl)- $\omega$ -hydroxypoly(oxy-1,2-ethanediyl) and  $\alpha$ -(1-oxo-2-propenyl)- $\omega$ -methoxypoly[oxy(methyl-1,2-ethanediyl)] (9CI) (CA INDEX NAME)

CM 1

CRN 83844-54-6

CMF (C3 H6 O)n C4 H6 O2

CCI IDS, PMS

$$H_2C = CH - C - C - C_3H_6) - n$$
 OMe

CM 2

CRN 26403-58-7

CMF (C2 H4 O)n C3 H4 O2

CCI PMS

$$H_2C = CH - C - O - CH_2 - CH_2 - OH_2 - O$$

CM 3

CRN 1996-88-9 CMF C14 H9 F17 O2

$$\begin{array}{c|c} & \text{O} & \text{CH}_2 \\ \parallel & \parallel \\ \text{F}_3\text{C---} (\text{CF}_2) & \text{7---} \text{CH}_2\text{---} \text{CH}_2\text{---} \text{O---} \text{C---} \text{Me} \end{array}$$

L19 ANSWER 4 OF 6 CAPLUS COPYRIGHT 2004 ACS on STN

ACCESSION NUMBER:

1998:335551 CAPLUS

DOCUMENT NUMBER:

129:54119

TITLE:

N-Polyfluoroalkyl-substituted (meth)acrylamides, their

(polymer) films, and photoresists using the

same

INVENTOR(S):

Miyashita, Tokuji

PATENT ASSIGNEE(S):

Chisso Corp., Japan; Miyashita, Tokuji

SOURCE:

Jpn. Kokai Tokkyo Koho, 11 pp.

CODEN: JKXXAF

DOCUMENT TYPE:

Patent Japanese

LANGUAGE:

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

duplicate DATE

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
JP 10139747	A2	19980526	JP 1996-312953	19961108
PRIORITY APPLN. INFO.:			JP 1996-312953	19961108
OTHER SOURCE(S):	MARPAT	129:54119		

208589-71-3P

RL: PRP (Properties); SPN (Synthetic preparation); TEM (Technical or engineered material use); PREP (Preparation); USES (Uses)

(LB films of N-polyfluoroalkyl(meth)acrylamides and their polymers with good water repellency, photosensitivity, and slip property)

RN 208589-71-3 CAPLUS

CN 2-Propenamide, N-(3,3,4,4,5,5,6,6,7,7,8,8,9,9,10,10,10heptadecafluorodecyl)-, homopolymer (9CI) (CA INDEX NAME)

CM 1

CRN 208589-64-4 CMF C13 H8 F17 N O

$$_{1}^{\circ}$$
 F<sub>3</sub>C- (CF<sub>2</sub>)<sub>7</sub>-CH<sub>2</sub>-CH<sub>2</sub>-NH-C-CH=-CH<sub>2</sub>

L19 ANSWER 5 OF 6 USPATFULL on STN

ACCESSION NUMBER:

2002:59638 USPATFULL

TITLE:

Top coating for synthetic leathers

INVENTOR(S):

Huang, Hsu-Nan, Newark, DE, UNITED STATES

	NUMBER	KIND	DATE	
PATENT INFORMATION:	US 2002033468	A1	20020321	
APPLICATION INFO.:	US 2001-970478	A1	20011004	(9)

RELATED APPLN. INFO.:

Division of Ser. No. US 2000-495132, filed on 31 Jan

2000, PENDING

NUMBER DATE -----

PRIORITY INFORMATION:

US 1999-123601P 19990310 (60)

DOCUMENT TYPE: Utility FILE SEGMENT: APPLICATION

LEGAL REPRESENTATIVE: E I DU PONT DE NEMOURS AND COMPANY, LEGAL DEPARTMENT -

PATENTS, 1007 MARKET STREET, WILMINGTON, DE, 19898

NUMBER OF CLAIMS: 11 EXEMPLARY CLAIM: LINE COUNT: 1042

CAS INDEXING IS AVAILABLE FOR THIS PATENT.

292849-59-3P

(water- and oil-repellent coating compns. for synthetic grain leather)

RN 292849-59-3 USPATFULL

CN 2-Propenoic acid, 2-methyl-, 2-hydroxyethyl ester, polymer with 3,3,4,4,5,5,6,6,7,7,8,8,9,9,10,10,10-heptadecafluorodecyl 2-propenoate, N-(hydroxymethyl)-2-propenamide and  $\alpha$ -(2-methyl-1-oxo-2-propenyl)ω-hydroxypoly(oxy-1,2-ethanediyl), graft (9CI) (CA INDEX NAME)

CRN 27905-45-9 CMF C13 H7 F17 O2

CM 2

CRN 25736-86-1

CMF (C2 H4 O)n C4 H6 O2

CCI PMS

$$\begin{array}{c|c} {\rm H_2C} & {\rm O} \\ \parallel & \parallel \\ {\rm Me-C-C} & {\rm O-CH_2-CH_2- \\ \end{array} \end{array} \begin{array}{c} {\rm OH} \\ {\rm OH} \\ \end{array}$$

CM 3

CRN 924-42-5 CMF C4 H7 N O2

CM 4

CRN 868-77-9 CMF C6 H10 O3

$$^{\rm H_2C}$$
 O  $^{\rm H_2}$   $^{\rm H_2}$   $^{\rm Me-}$  C- C- O- CH $_2$  - CH $_2$  OH

L19 ANSWER 6 OF 6 USPATFULL on STN

ACCESSION NUMBER:

2002:45669 USPATFULL

TITLE:

Top coating for synthetic leathers

INVENTOR(S):

Huang, Hsu-Nan, Newark, DE, United States

PATENT ASSIGNEE(S): E. I. du Pont de Nemours and Compa

E. I. du Pont de Nemours and Company, Wilmington, DE,

United States (U.S. corporation)

NUMBER

DATE

PRIORITY INFORMATION: US 1999-123601P 19990310 (60)

Utility

DOCUMENT TYPE:

GRANTED

FILE SEGMENT:

Yoon, Tae H.

PRIMARY EXAMINER:

NUMBER OF CLAIMS:

EXEMPLARY CLAIM:

NUMBER OF DRAWINGS:

0 Drawing Figure(s); 0 Drawing Page(s)

LINE COUNT:

1019

CAS INDEXING IS AVAILABLE FOR THIS PATENT.

## IT 292849-59-3P

(water- and oil-repellent coating compns. for synthetic grain leather)

RN292849-59-3 USPATFULL CN

2-Propenoic acid, 2-methyl-, 2-hydroxyethyl ester, polymer with 3,3,4,4,5,5,6,6,7,7,8,8,9,9,10,10,10-heptadecafluorodecyl 2-propenoate, N-(hydroxymethyl)-2-propenamide and  $\alpha$ -(2-methyl-1-oxo-2-propenyl)ω-hydroxypoly(oxy-1,2-ethanediyl), graft (9CI) (CA INDEX NAME)

CM 1

CRN 27905-45-9 CMF C13 H7 F17 O2

CM 2

CRN 25736-86-1

CMF (C2 H4 O)n C4 H6 O2

CCI

$$\begin{array}{c|c} ^{H_2C} & \text{O} \\ & \parallel & \parallel \\ \text{Me} - \text{C} - \text{C} \end{array} \begin{array}{c} \text{O} - \text{CH}_2 - \text{CH}_2 \\ \hline & \text{n} \end{array}$$

CM

CRN 924-42-5 CMF C4 H7 N O2

$$\begin{array}{c} \text{O} \\ \parallel \\ \text{HO- CH}_2\text{-- NH- C- CH-----} \text{ CH}_2 \end{array}$$

CM

CRN 868-77-9 CMF C6 H10 O3

$$\begin{array}{c} ^{\rm H_2C} \quad {\rm o} \\ \parallel \quad \parallel \\ {\rm Me-} \quad {\rm C-} \quad {\rm C-} \quad {\rm o-} \quad {\rm CH_2-} \quad {\rm CH_2-} \quad {\rm OH} \end{array}$$